

Filed Via Express Mail

Rec. No.:

On:

By:

Brendy Belony

Any fee due as a result of this paper, not covered by an enclosed check, may be charged on Deposit Acct. No. 50-1290.

**Attorney Docket No.: NECF 17.638B**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor: Mami MIYASAKA

Serial No.:

Filed:

Title: **ELECTRON BEAM EXPOSURE MASK, ELECTRON BEAM EXPOSURE METHOD, METHOD OF FABRICATING SEMICONDUCTOR, AND ELECTRON BEAM EXPOSURE APPARATUS**

Examiner:

Group Art Unit:

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

S I R :

Prior to examination on the merits and prior to calculation of the filing fee, please amend the above-captioned application as follows: